In re Patent Application of: COFFA ET AL.
Serial No. 10/014,880
Confirmation No. 2364
Filed: DECEMBER 11, 2001

In the Specification:

Please replace the title beginning at page 1, line 1, with the following new title:

--METHOD OF FABRICATING PRESSURE SENSOR MONOLITHICALLY INTEGRATED--

Please replace the Abstract of the Disclosure on page 15 with the Abstract attached hereto.

Please replace the paragraph beginning at page 10, line 9, with the following rewritten paragraph:

The diaphragm of the pressure sensor provided by the epitaxial layer overhanging the microphone cavity formed with the method of this invention may have any shape. For example, it may be in the form of concentric circular sectors, each 100 μ m wide, as depicted in Fig. [[5]] 4.

Please replace the paragraph beginning at page 10, line 19, with the following rewritten paragraph:

A further object of the invention is that of providing a monolithically integrated system, as the one depicted in Fig. [[6]] 5, for sensing the direction of the source of a sound wave and its intensity by analyzing the signals produced by an array of monolithically integrated pressure sensors of the invention,

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disposed at different locations of the same chip, and using the circuit blocks schematically shown in Fig. [[6]] 5.

Please replace the paragraph beginning at page 10, line 28, with the following rewritten paragraph:

The distinct pressure sensors of the system, which in the embodiment of Fig. [[6]] 5 are only two but which may be even more numerous, will produce at different instants an electrical signal representative of the vibration induced on their diaphragm. The direction of the source of a sound wave as sensed by the various pressure sensors of the integrated system of the invention is determined on the basis of the relative delays with which distinct sensors detect the sound wave.